

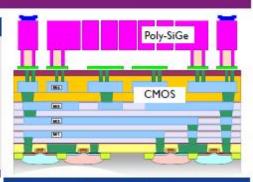


Background

In imec's 200mm fab a dedicated poly-SiGe above-IC MEMS (Micro Electro-Mechanical Systems) platform has been set up to integrate MEMS and its readout and driving electronics on one chip. This monolithic approach results in more compact systems with a reduced assembly and packaging cost and a higher performance than current hybrid systems.

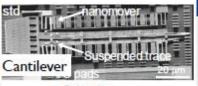
Platform

The SiGe MEMS platform consists of a number of standard modules: CMOS protection layer, MEMS via and poly-SiGe electrode, anchor and poly-SiGe structural layer and an optional thin-film poly-SiGe packaging module. Extra modules, such as a piezoresistive layer (see exhibit #I) can be added depending on the functionality that is needed.



gyroscope

SiGeM project with Bosch, ASM, Philips (now NXP), IMSE-CNM



Project with Intel and Nanochip



Project with Panasonic



Project with ASML, NXP, Bruco, Philips Applied Technologies

Demonstrators

With this platform and together with our partners, several successful demonstrators have been built already. Examples are an integrated gyroscope for automotive applications (exhibit #2), a reliable 11 megapixel micro-mirror array for high-end industrial applications (exhibit #3), a cantilever array for probebased data storage, SiGe thin film packaged SOI resonators with quality factors >200 000, ...

CMORE Production Prototyping (Co-)development Process High-volume Prototyping development Product Concept Low-volume manufacturing **Packaging** Transfer **Oualification** prototyping @ foundry Design Testing @ imec partner Reliability

CMORE service

This SiGe platform is one of the technologies that imec offers to industrial customers through our CMORE service. Within CMORE innovative concepts are turned into products. Academic customers can make use of the SiGe MPW service within Europractice (exhibit #4)

